LISTING OF THE CLAIMS:

This listing of claims will replace all prior versions and listings of claims in the application:

Claim 1. (Currently amended) An apparatus for forming an alignment layer on a substrate of a liquid crystal display, comprising:

means for generating an ion beam or an atomic beam;

masks interposed between the substrate and the generating means, and respectively including an edge in a shape based on the orientation direction at each position of an the alignment layer, said shape being defined across an entire width of the alignment layer; and a slit formed by a plurality of edges of the masks.

- Claim 2. (Original) The apparatus according to claim 1, wherein the shape of one of said edges is determined by integrating the orientation direction of liquid crystals in forming an alignment layer using a linear edge perpendicular to the moving direction of the substrate along the linear edge.
- Claim 3. (Currently amended) The apparatus according to claim 1, wherein one of said edges provided on the end side of the <u>a</u> moving direction of the substrate includes a shape based on the distribution of the orientation direction of liquid crystals and the other <u>another of said</u> edges provided on the <u>a</u> starting side of the <u>movement moving</u> direction of the substrate is in a linear shape.
- Claim 4. (Currently amended) The apparatus according to claim 1, wherein said edges provided on the <u>a</u> starting <u>side</u> and <u>an</u> end sides of the <u>a</u> moving direction of the substrate are in the same shape.
- Claim 5. (Currently amended) The apparatus according to claim[[s]] 1, wherein said edges respectively include a curve shape.

Claim 6. (Currently amended) An apparatus for forming an alignment layer on a substrate of a liquid crystal display comprising:

means for generating an ion beam or an atomic beam;

a plurality of masks interposed between the substrate and the generating means; and a slit formed by a plurality of edges of the masks,

wherein one of the edges of said masks projected on said substrate has a shape based on the orientation direction of liquid crystals at each position of said alignment layer, wherein the shape of the edge projected on said substrate is determined by integrating the orientation direction of liquid crystals in forming an alignment layer using a linear edge perpendicular to a moving direction of the substrate along the linear edge.

Claim 7. (Cancelled)

- Claim 8. (Currently amended) The apparatus according to claim 6, wherein the shape of said edge of the mask projected on a substrate, one of said edges being provided on the an end side of the moving direction of the substrate[[,]] includes a shape based on the a distribution of the orientation direction of liquid crystals, and the other another of said edges being provided on the a starting side of the moving direction of the substrate is in a linear shape.
- Claim 9. (Currently amended) The apparatus according to claim 6, wherein said edges provided on the <u>a</u> starting <u>side</u> and <u>an</u> end sides of the moving direction of the substrate are in the same shape.
- Claim 10. (Original) The apparatus according to claims 6, wherein said edges respectively have a different distance from the substrate at each position, and one of said edges projected on the substrate includes a curve shape.

Claim 11. (Cancelled).

Claim 12. (Cancelled)

Claim 13. (New) An apparatus for forming an alignment layer on a substrate of a liquid crystal display, comprising:

an irradiation source; and

a mask between the substrate and the irradiation source, said mask being deformed in a plane perpendicular to the substrate.

- Claim 14. (New) The apparatus according to claim 13, further comprising an external force exerted on said mask for deforming the mask.
- Claim 15. (New) The apparatus according to claim 13, wherein said mask is dynamically deformable.
- Claim 16. (New) The apparatus according to claim 13, wherein said mask comprises an edge that is deformed in a plane parallel to the substrate.
- Claim 17. (New) The apparatus according to claim 16, further comprising an external force exerted on said mask for deforming the mask.
- Claim 18. (New) The apparatus according to claim 16, wherein said mask is dynamically deformable.